

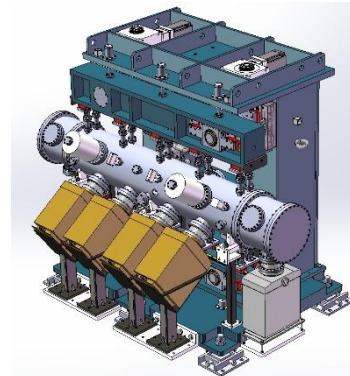


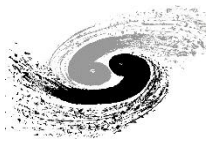
The status of Insertion Devices magnetic field measurement at HEPS

ChenWan

IHEP

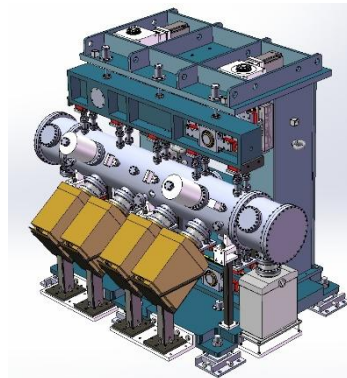
Sep. 26. 2022



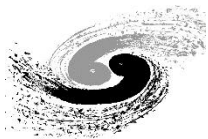


Outline

- Overview of HEPS and Insertion Devices
- Magnetic measurement laboratory for Insertion Devices
- Instruments of Insertion Devices magnetic measurement
- Summary



Overview of HEPS and ID System



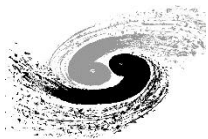
HEPS introduction

- HEPS will be the first high-energy synchrotron radiation light source in China.
- HEPS is a high-performance and high-energy synchrotron radiation light source with a beam energy of 6GeV and an ultra-low emittance of better than 60pm·rad.
- the project will be completed by the end of 2025.



Main parameters of HEPS

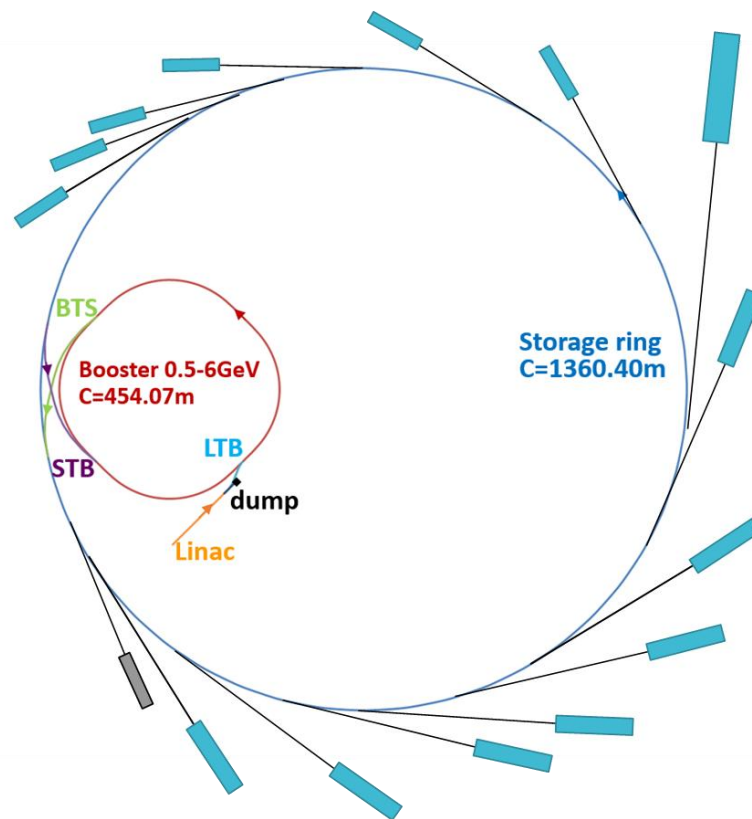
Beam energy [GeV]	6
Circumference [m]	~1360
Emittance [nm·rad]	0.06
Beam current [mA]	200
Cell units	48
Injection	Top-up
Brightness [phs/s/mm ² /mrad ² / 0.1%BW]	>10 ²²

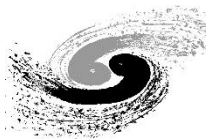


Insertion Devices at first stage

- 14 beamlines for HEPS ,6 different types,totally 19 insertion devices

type	quantity
CPMU	6
IVU	5
IAU	4
IAW	2
AK	1
Mango	1

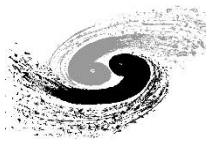




Main Parameters of HEPS ID Beamlines

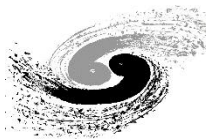
BL No.	Beamline	SS No.	ID Type	Length [m]	ID No.	Period Length [mm]	B0[T]	Gap Range [mm]	Min. Phase Error RMS [Degree]	Photon Energy [keV]	β
B1(A)	Engineering Materials Beamline	ID07	CPMU	2	1	16.7	1.19	5.2-10	3	50-170	Low
B1(B)			CPMU	2	1	16.7	1.19	5.2-10	3		
B2	Hard X-ray Nanoprobe Multimodal Imaging Beamline	ID19	IVU(SmCo)	4	1	22.6	1.1	5.2-15.2	3	4.8-40	Low
B3(A)	Structural Dynamics Beamline	ID23	CPMU	2	1	12	0.81	5.2-7.0	4	20.9-24, 62.7-72	Low
B3(B)			CPMU	2	1	14.2	1.00	5.2-9.9	4	14.4-20.9, 43-62.7	
B4	Hard X-ray Coherent Scattering Beamline	ID09	IVU(SmCo)	4	1	19.9	0.97	5.2-14.0	3	7.33-13.34, 22-40	Low
B5	Hard X-Ray High Energy Resolution Spectroscopy Beamline	ID33	IVU(NdFeB)	4	1	18.6	1.04	5.2-13.0	4	7.1-16.88, 21.3-25	Low
B6	High Pressure Beamline	ID31	IVU(SmCo)	4	1	19.9	0.97	5.2-8.0	3	20-50	Low
B7(A)	Hard X-Ray Imaging Beamline	ID21	CPMU	2	1	18.8	1.35	5.2-13.1	3	10-90	Low
B7(B)			Wiggler	1	1	73	1.64	11	--	40-300	
B7-C			Mango Wiggler	1	1	50.7/50.0	1	11			
B8	X-ray Absorption Spectroscopy Beamline	ID46	IAU	5	1	35	0.88	11-24.5	4	4.8-45	High
B9	Low-Dimension Structure Probe Beamline	ID05	IVU(SmCo)	4	1	22.6	1.1	5.2-15.2	3	4.8-40	Low
BA	Microfocussing X-Ray Protein Crystallography Beamline	ID02	IAU	5	1	32.7	0.8	11-22.8	4	5-18	High
BB	Pink Beam SAXS Beamline	ID08	IAU	5	1	25	0.54	11.2-17.5	6	8-12, 24-33	High
BC	High Resolution Nanoscale Electronic Structure Spectroscopy Beamline	ID41	APPLE-KNOT	5	1	256.8		11	5	0.2-2	Low
BE	Transmission X-Ray Microscopy Beamline	ID30	IAU	5	1	32.7	0.8	11-21.2	4	5-15	High
BF(A)	Test Beamline	ID42	CPMU	2	1	22.8	1.18	7.2-16.0	3	10-90	High
BF(B)			Wiggler	1	1	73	1.64	11	--	40-300	

Magnetic measurement laboratory for Insertion Devices



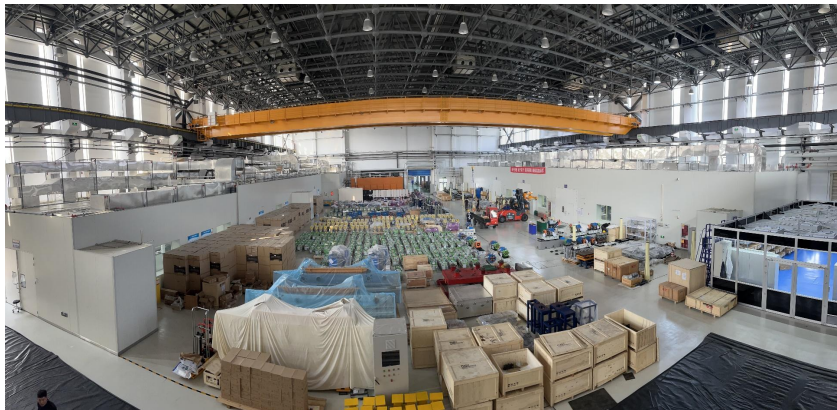
New labs of insertion devices

- Totally 19 insertion devices,
- need to be completed in Apr.2024
- The existing lab is not big enough for accommodate the full HEPS insertion devices
- Construct new labs and new measurement systems



New labs of insertion devices

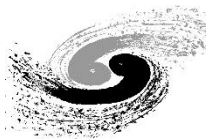
- new labs located in Magnet Technology Hall of PAPS
- PAPS(Platform of Advanced Photon Source Technology R&D) near HEPS



Magnet Technology Hall



overlook of HEPS and PAPS



New labs of insertion devices

- Room with Temperature Regulation of $25\text{C}^{\circ} \pm 0.1\text{C}^{\circ}$
- the roof of the lab can be open or closed automatically

In air ID and CPMU Lab 110m²	Storage ring magnet measurement Lab	power supply Lab
		IVU Lab 75m²



In air ID and CPMU lab



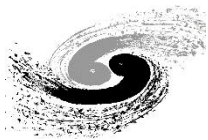
IVU lab

Magnetic measurement systems



Magnetic measurement systems in used

	IAW	IAU	IVU	CPMU	AK	MANGO	system Status
1# Hall Probe bench		●		●			work
2#Hall probe bench	●	●	●	●	●		work
3m In-Situ Hall Probe measurement system				●			work
5m In vacuum Hall Probe measurement system			●				In commissioning
Lateral support Stretched Wire	●	●	●		●	●	work
Symmetrical support Stretched Wire			●	●			1 work 1Under development
Longitudinal probe Hall system						●	

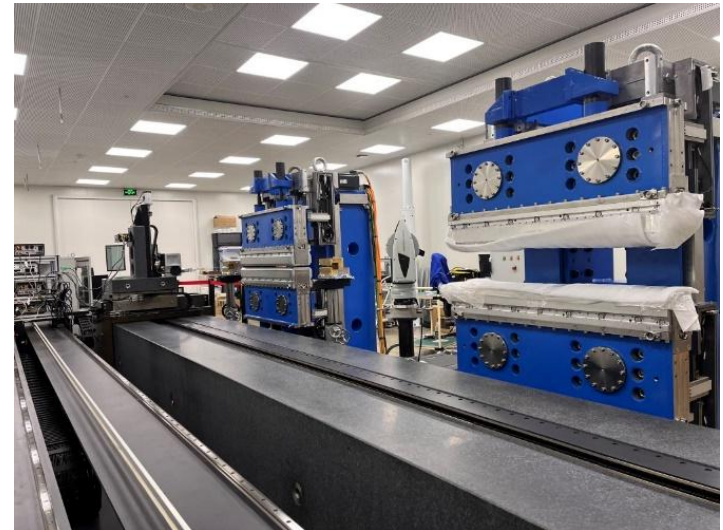


Hall probe measurement benches for in air ID

- 2 Hall probe measurement benches
 - 6.5m motion stroke
 - 3-D Hall sensor
 - X,Y,Z,A,C 5 motion axes
 - A and C axes are useful for fine angular positioning of the Hall sensor



1#Hall Probe bench in YuQuanlu lab

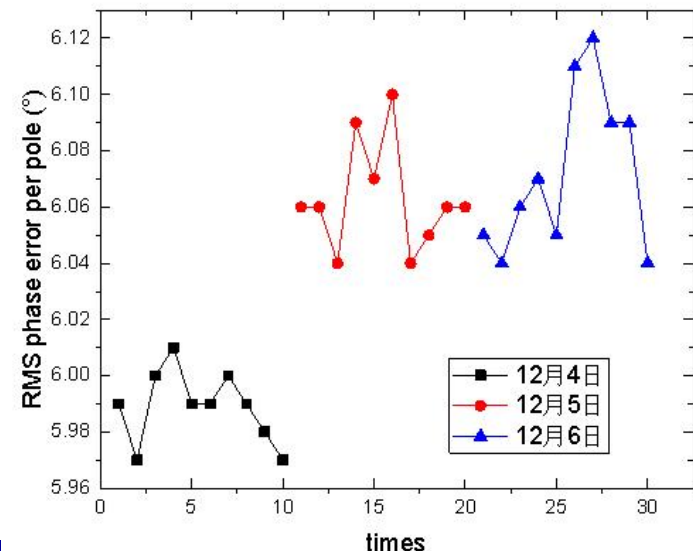


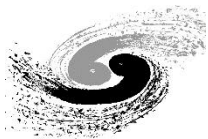
2# Hall Probe bench in PAPS lab



Hall probe measurement benches for in air ID

- Z axis Flatness deviation $< \pm 10 \mu\text{m}$
- Z axis Positioning accuracy: $< \pm 1.5 \mu\text{m}$
- RMS phase error :
 - 10 times RMS repeatability: $< 0.02^\circ$
 - 3 days reproducibility: $< 0.16^\circ$





Stretched Wire for In air insertion devices

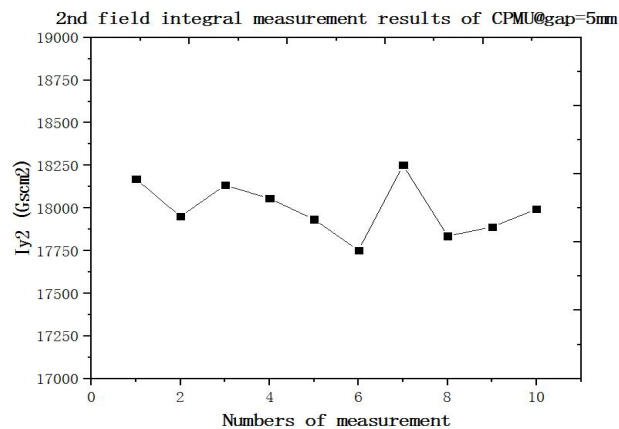
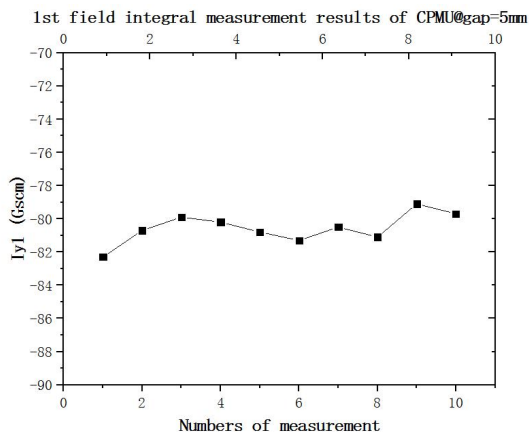
➤ Latgeral support Stretched Wire system

➤ 2182A nanometer

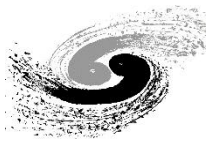
➤ 2-D newport motion stages



	$\Delta I1(\text{Gscm})$	$\Delta I2(\text{Gscm}^2)$
short term	<1	<300
long term(5days)	<4	<500



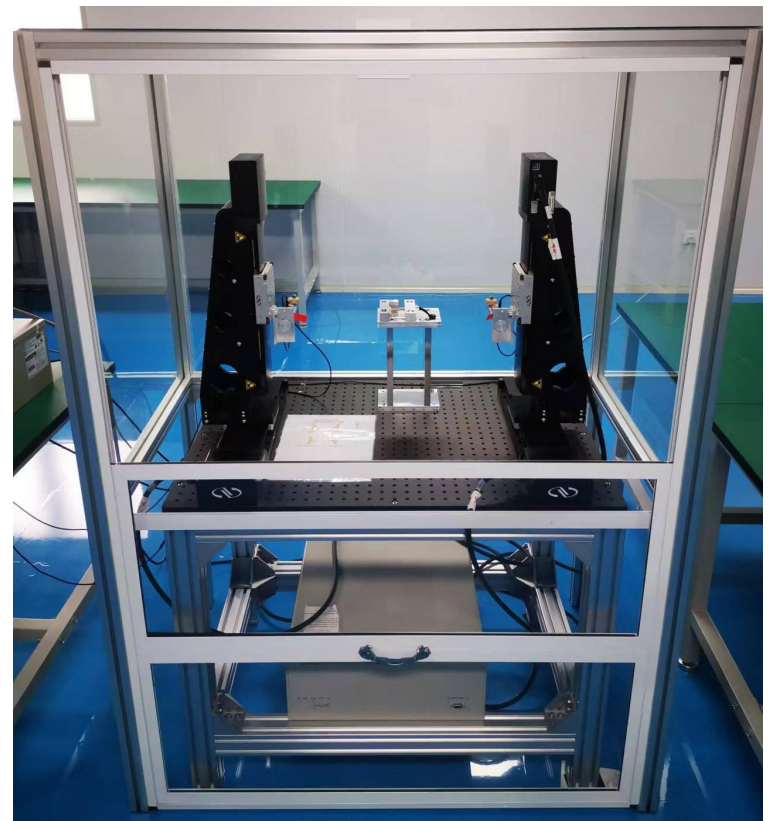
5 days long term error of I1 and I2



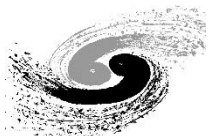
Stretched Wire for In air insertion devices



magnet girder measurement



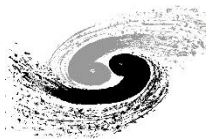
single magnet block measurement



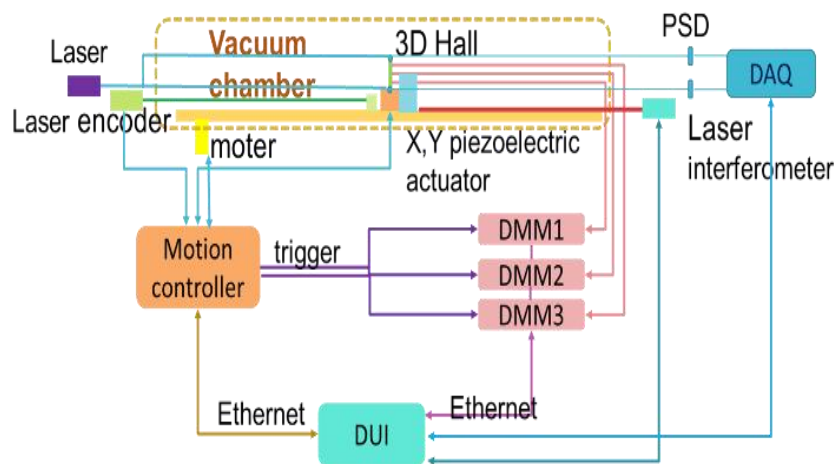
CPMU measurement system

- 3m In-Situ Hall probe system
- Symmetrical support SW

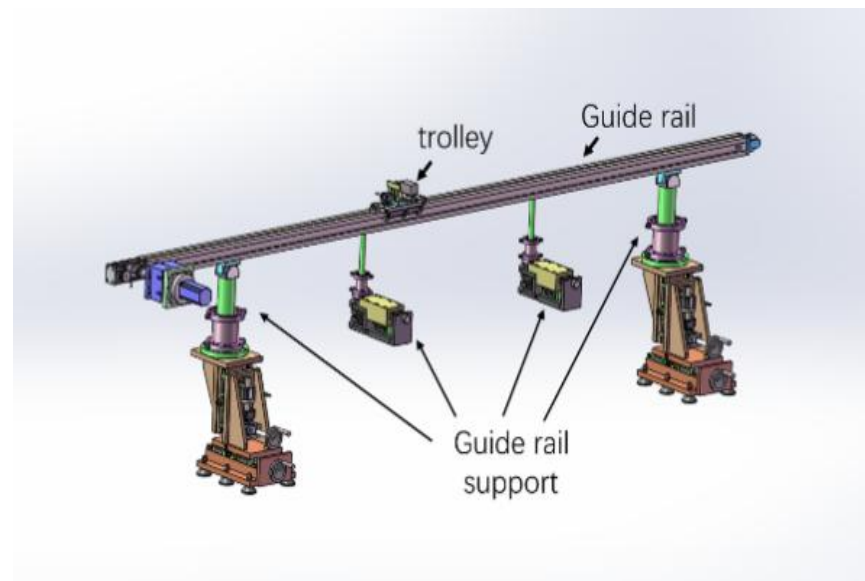




3m In-Situ Hall probe system



The System schematic layout of Hall probe measurement system

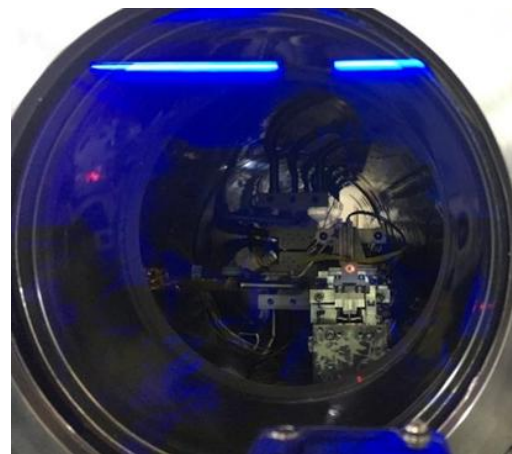
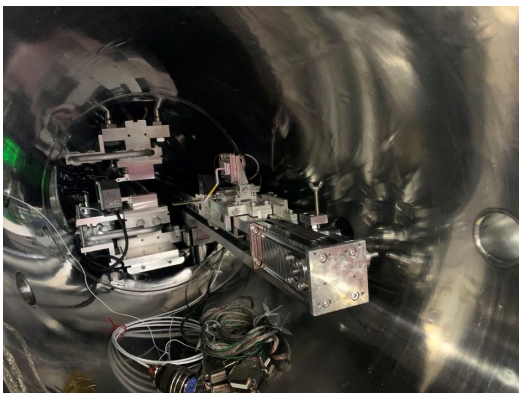


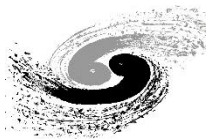
The three-dimensional diagram of four-point support guide rail structure



In-Situ Hall probe system

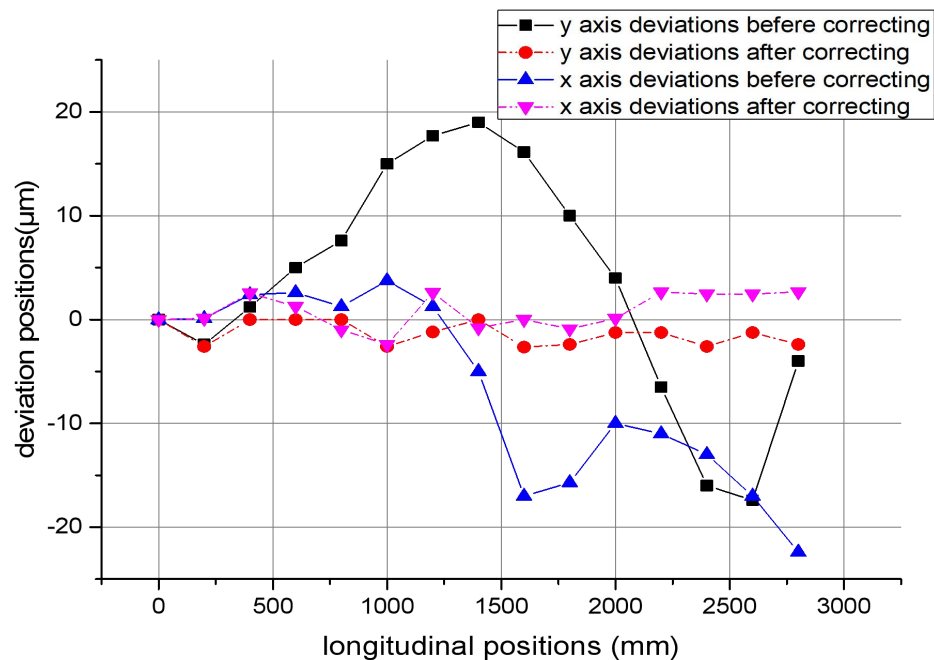
- Two dimensional piezoelectric stages, Hall probe, optical mirror, pinhole, etc. are placed on the trolley
- The strokes of piezoelectric stages in X and Y directions are 26mm and 12mm respectively, which are used for CPMU magnetic center scanning and guide rail straightness error dynamic compensation.

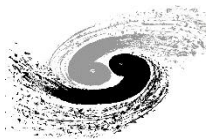




In-Situ Hall probe system

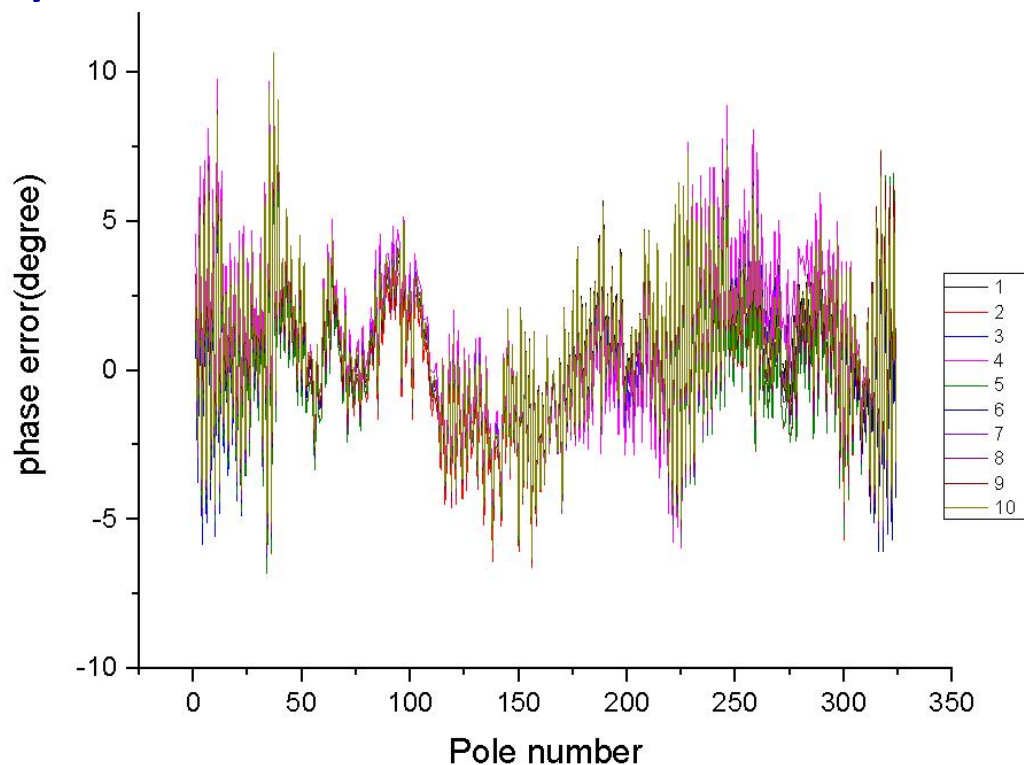
- The max error of x direction before and after compensation are $30\ \mu\text{m}$ and $6\ \mu\text{m}$; the max error of y direction before and after compensation are $40\ \mu\text{m}$ and $5\ \mu\text{m}$.





In-Situ Hall probe system

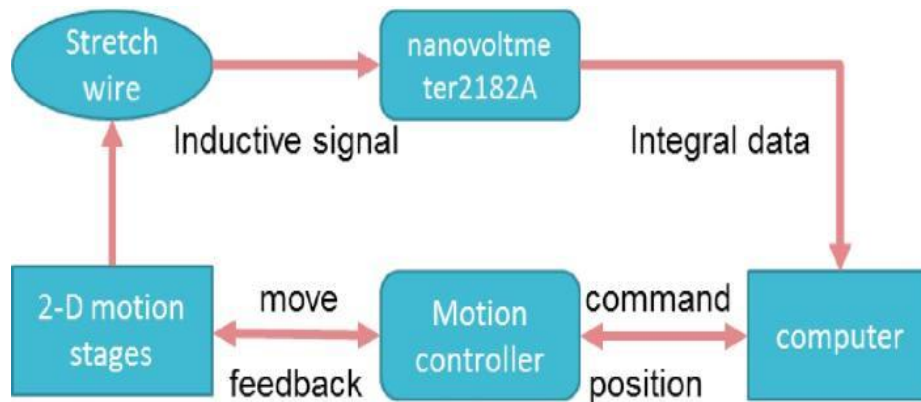
- 2m CPMU12@Gap5.2
- 10 times in-situ RMS phase error measurement repeatability is 0.034°

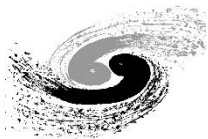




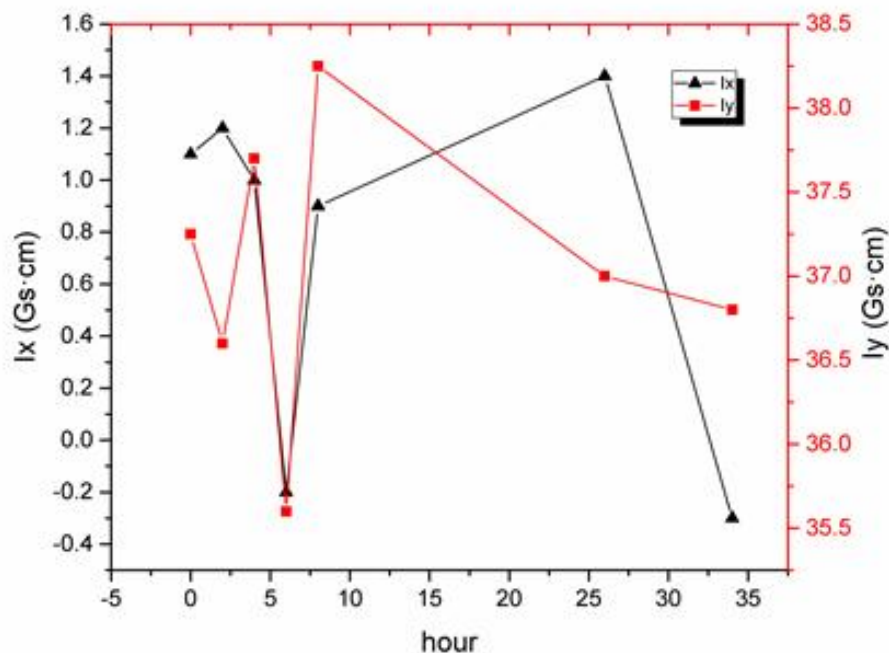
Stretched wire system

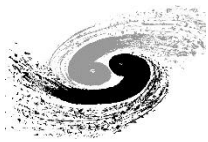
- symmetrical support structure Counteracts the effects of vacuum suction.





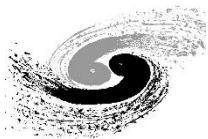
- horizontal and vertical first field integral measured by stretched wire system in 2 days. The maximum error of horizontal and vertical first field integral is 1.71 and 2.68 Gs·cm respectively.



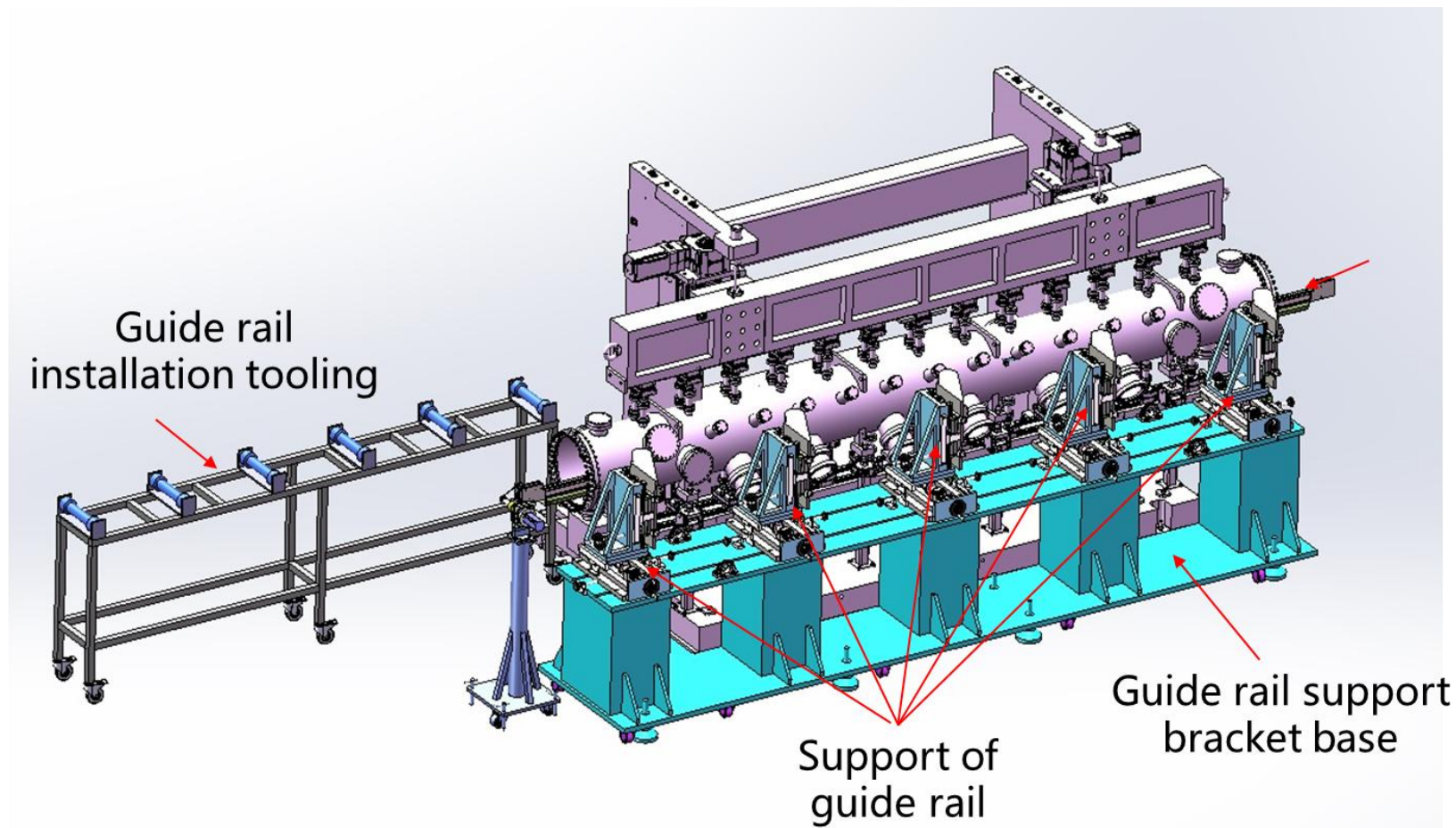


IVU measurement sytem

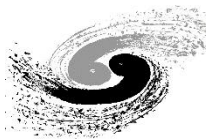
- 4.8m in-Situ Hall probe measurement system
- symmetrical support SW, same as the SW of CPMU



4.8m in-Situ Hall probe easurement system

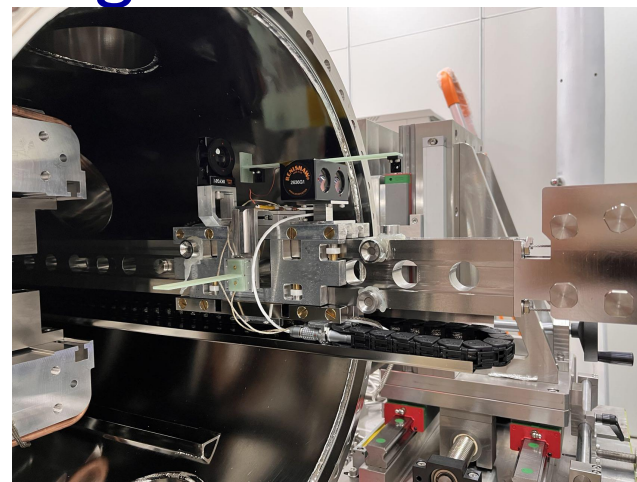


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4.8m in-Situ Hall probe easurement system

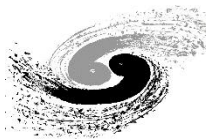
- the system is in commissioning





Summary

- 2 new magnet measurement laboratories are built to handle the insertion devices magnetic measurements.
- All measurements of IDs must be completed in April 2024.
- There are still many challenges of magnetic field measurement for IVU ,CPMU and AK.



*Thank You
for
Your Attention!*